

# Semitool 4400 L Spin Rinser Dryer

## 300 mm Spin Rinser Dryer

**The Semitool Model 4400L is the industry choice for low volume, high reliability rinsing and drying of 300 mm wafers.**

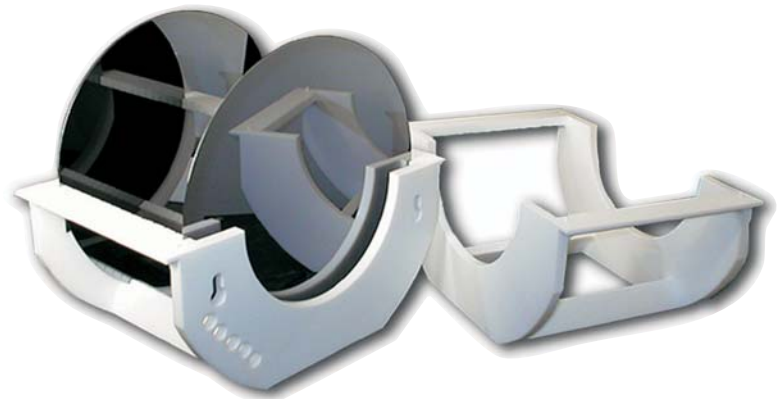
With its small footprint and ease-of-use, the 4400L is ideal for development centers, failure analysis labs, and other operations where manual processing of 300 mm wafers is required.

The Semitool 4400L utilizes an electropolished stainless steel process chamber which supports a full DI water spin-rinse cycle, followed by a hot N<sub>2</sub> spin-dry cycle. The tool includes:

- **Twin DI Water Rinse Manifolds** –  
*assuring full coverage of wafers during DI rinse*
- **On-board N<sub>2</sub> Heater & Point of Use N<sub>2</sub> Filter** –  
*minimizing particles*
- **CY-20 Anti-static Cell** –  
*reducing static charge on the process carrier and wafers*
- **RM-20 Resistivity Monitor** –  
*enabling "rinse to clean" process recipes*
- **WR-20B Water Recirculation** –  
*minimizing organic build-up in DI water lines*
- **PSC-102 Controller** –  
*programming and storing multiple process recipes*
- **Carrier Present Sensor** –  
*preventing operation of an unloaded tool*
- **DL-20 Door Lock** –  
*preventing access to the process chamber during operation*



**Optional clamshell  
shown with 300 mm wafers.**



## The Semitool 4400L is a complete process solution.

With an optional 13 wafer Clamshell Carrier (see photo above), wafers are fully protected throughout the entire spin rinse dry process. The Clamshell Carrier also provides more uniform DI and N<sub>2</sub> coverage of the wafers to optimize rinsing and promote rapid, water-spot free spin drying.

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## Throughput, Performance & Reliability

**With a proven design and minimal facility requirements, the Semitool 4400L delivers superior operating results:**

- Throughput: Typically 70-90 wafers an hour<sup>1</sup>
- Uptime: > 95%
- Footprint: 6.5 ft; 0.6 m

## Standard Features and Options

One Year Parts and Labor Warranty  
EPO Emergency Off Switch  
Earthquake Tiedowns  
Manual Door  
Six Bolt Rotor for Customer Carrier or Semitool Clamshell  
Manual on Clean Room Paper (option)  
Installation (option)  
CE Certification (option)

## Facility Requirements

DI Water: 30 to 35 psi; 3.5 to 4.6 GPM  
Nitrogen: 30 to 40 psi; 8.0 to 10.0 CFM  
Exhaust: 7 CFM  
Drain: 1.5 inch PVC Drain Box Fitting  
Electrical: Standard: 208 VAC, 3 phase, 20 amp<sup>2</sup>

***Dual DI water rinse manifolds assure full coverage of wafers during DI rinse. The chamber is built of electroplated 316 stainless steel for maximum contamination control.***



<sup>1</sup> Dependent on process time.  
<sup>2</sup> Voltage and current varies with country,  
Three phase power required, consult factory for specifics.

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